TITLE: EMITTER FOR ELECTRON-BEAM PROJECTION LITHOGRAPHY SYSTEM AND MANUFACTURING METHOD

THEREOF

INVENTOR(S): IN-KYEONG YOO ET AL ATTORNEY'S DOCKET NO: 030681-574

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FIG. 1 (PRIOR ART)

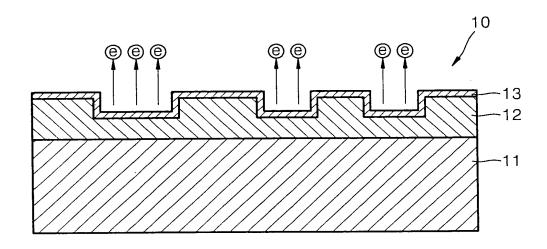
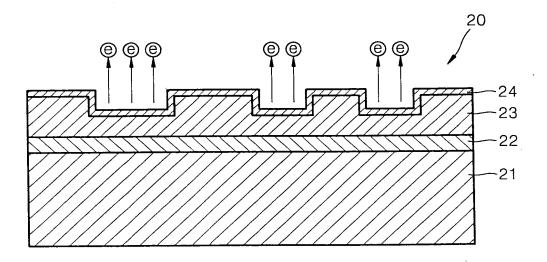


FIG. 2 (PRIOR ART)



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FIG. 3A (PRIOR ART)

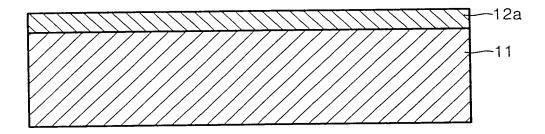


FIG. 3B (PRIOR ART)

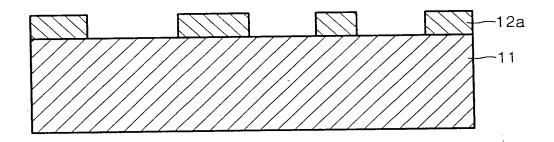
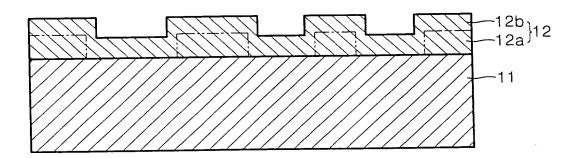


FIG. 3C (PRIOR ART)



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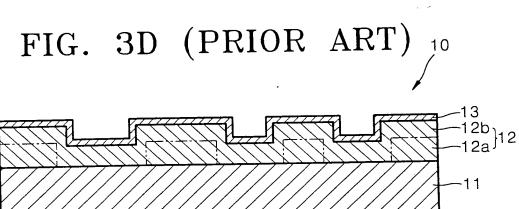
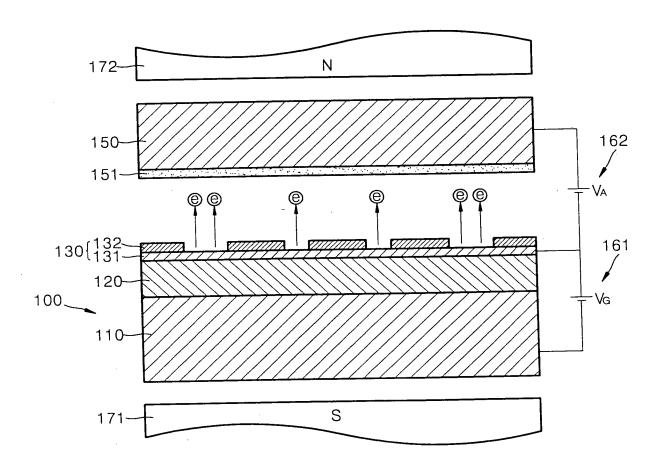


FIG. 4



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FIG. 5

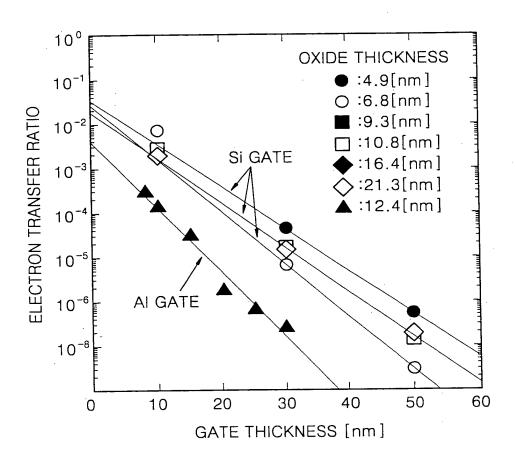
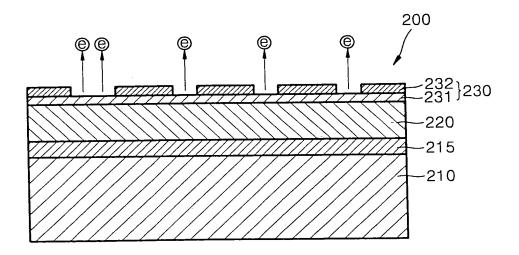


FIG. 6



TITLE: EMITTER FOR ELECTRON-BEAM PROJECTION LITHOGRAPHY SYSTEM AND MANUFACTURING METHOD

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FIG. 7A

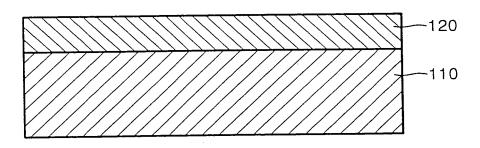


FIG. 7B

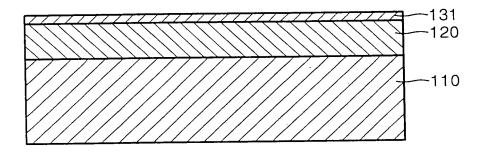
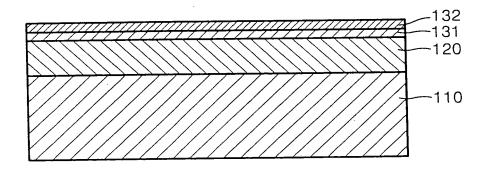


FIG. 7C



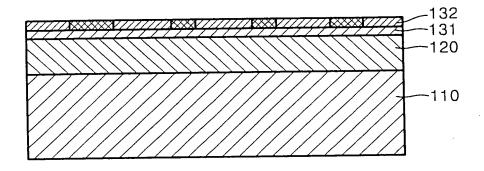
TITLE: EMITTER FOR ELECTRON-BEAM PROJECTION LITHOGRAPHY SYSTEM AND MANUFACTURING METHOD

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FIG. 7D



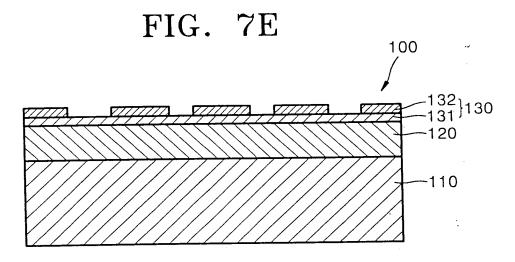
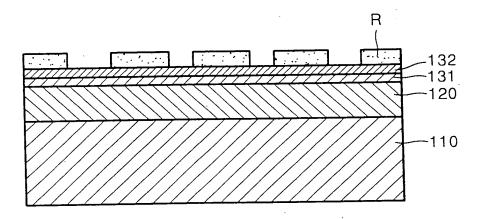


FIG. 7F



TITLE: EMITTER FOR ELECTRON-BEAM PROJECTION LITHOGRAPHY SYSTEM AND MANUFACTURING METHOD

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FIG. 7G

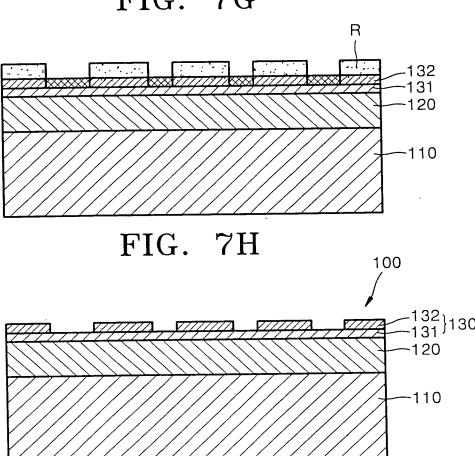
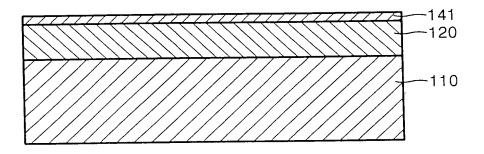


FIG. 8A



TITLE: EMITTER FOR ELECTRON-BEAM PROJECTION LITHOGRAPHY SYSTEM AND MANUFACTURING METHOD

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FIG. 8B

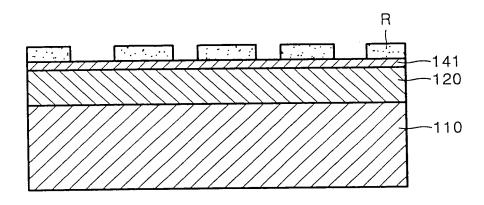


FIG. 8C

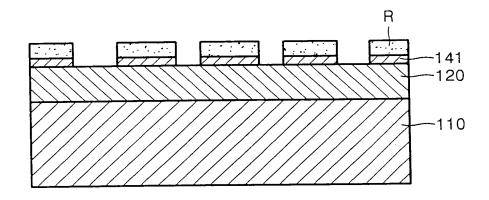
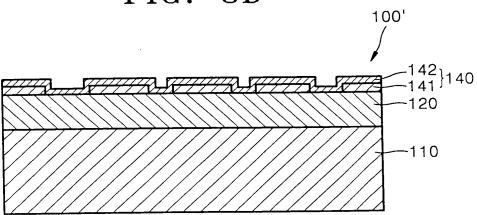


FIG. 8D



TITLE: EMITTER FOR ELECTRON-BEAM PROJECTION LITHOGRAPHY SYSTEM AND MANUFACTURING METHOD THEREOF

INVENTOR(S): IN-KYEONG YOO ET AL

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FIG. 9A

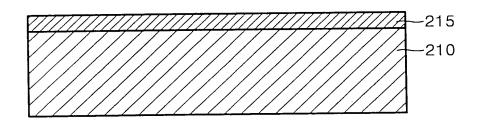


FIG. 9B

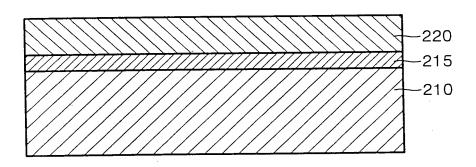


FIG. 9C

